

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Inventor: Apostolos Voutsas

Serial No.: Not Yet Assigned

Filed: Herewith

Title: METHOD FOR FORMING
SILICON FILMS WITH
TRACE IMPURITIES

PATENT APPLICATION

Attorney Docket No.
SLA 0592

Stevens
#2
9-2601



Hon. Assistant Commissioner for Patents
Washington, D.C. 20231

INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. §1.97

Sir:

Listed on attached Form PTO-1449 is information submitted pursuant to
37 C.F.R. §1.56. A copy of each listed publication is submitted herewith.

Applicant respectfully requests that the listed information be considered by
the Examiner and made of record in the above-identified application.

(Date)

June 28, 2001

Respectfully submitted,

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